

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

USPTO
OCT 31 2003
PATENT & TRADEMARK OFFICE
RECEIVED
NOV 10 2003
AC 1700

Inventors: Pablo I. Rovira
Assignee: Nanometrics Incorporated
Title: Optical Metrology System with Combined Interferometer and Ellipsometer
Serial No.: 10/016,943 Filing Date: December 13, 2001
Examiner: Samual A. Turner Group Art Unit: 2877
Docket No.: NAN051 US Confirmation No.: 7400

Mail Stop Non-Fee Amendment
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Santa Clara, California
October 31, 2003

RECEIVED
NOV 12 2003
CHIOLLOGY CENTER 2800

RESPONSE TO OFFICE ACTION

Dear Sir:

This Response to Office Action is responsive to the August 20, 2003, Office Action, which has a statutorily shortened period for response that ends November 20, 2003. Please enter the following amendments before taking action on the merits of the above-referenced application.

SILICON VALLEY
PATENT GROUP LLP

2350 Mission College Blvd.
Suite 360
Santa Clara, CA 95054
(408) 982-8200
FAX (408) 982-8210